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INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

#2

APPLICANT

Lukanc et al.

FILING DATE

12/11/2001
Unknown

GROUP ART UNIT

Unknown 1756

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE
	A1	09/772,527		Todd Lukanc			01/30/2001
<i>nm</i>	A2	6,228,539 B1	05/08/2001	Wang et al.	430	5	
<i>nm</i>	A3	5,858,580	01/12/1999	Wang et al.	430	5	
<i>nm</i>	A4	5,807,649	09/15/1998	Liebmann et al.	430	5	
<i>nm</i>	A5	5,573,890	11/12/1996	Spence	430	311	

 1046 U.S. PTO
 10/016439
 12/11/01

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

<i>nm</i>	A6	✓	Levenson et al., "Improving Resolution in Photolithography with a Phase-Shifting Mask," IEEE Transactions On Electron Devices, Vol. ED-29, No. 12, December 1982, pp. 1828-36.					
<i>nm</i>	A7	✓	Lin, B.J., "Phase-Shifting Masks Gain an Edge," Circuits & Devices, March 1993, pp. 28-35.					

EXAMINER

W. G. G. G.

DATE CONSIDERED

9/24/03

* EXAMINER: Initial if citation considered, whether or not citation is in compliance with MPEP 609; Draw line through citation if not in compliance and not considered. Include any copy of this form with next

Substitute for form 1449B/PTO
INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

Date Submitted: May 24, 2009

(use as many sheets as necessary)

Sheet	1	of	1
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Complete if Known

Application Number	10/016,439
Filing Date	12/11/2001
First Named Inventor	Todd P. Lukanc
Group Art Unit	1756
Examiner Name	Unknown
Attorney Docket Number	039153-0447 (G1152)

U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ⁶
	A5/✓	Levenson et al., "Improving Resolution in Photolithography with a Phase-Shifting Mask," IEEE Transactions on Electron Devices, Vol. ED-29, No. 12, December 1982, pp. 1828-1836.	
	A6/✓	Lin, B.-J., "Phase-Shifting Masks Gain an Edge," Circuits & Devices, March 1993, pp. 28-35.	

**Examiner
Signature**

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Considered

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5 Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶Applicant is to place a check mark here if English language Translation is attached.

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